



IPW AF/1246

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshihito Tsuga, et al. Docket No: TI-31620
Serial No: 10/085,753 Conf. No: 8409
Examiner: Michail Kornakov Art Unit: 1746
Filed: 02/28/2002
For: METHOD AND DEVICE FOR REMOVING PARTICLES ON SEMICONDUCTOR WAFERS

AMENDMENT PURSUANT TO 37 CFR 1.116

Mail Stop AF
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. § 1.8(a)
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 5-11-04.

Ann Trent
Ann Trent

Dear Sir:

Responsive to the Office Action mailed March 12, 2004, in connection with the above identified application, Applicants respectfully submit the following amendments and remarks.